12-26-01



Atty. Docket No. AMAT/5813/ETCH/METAL/JB

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application Assistant Commissioner of Patents and Trademarks Washington, D.C. 20231

Re:

Inventor(s):

Melisa Buie; Brigitte Stoehr; and Guenther Ruhl

Title:

ETCH PROCESS FOR PHOTOLITHOGRAPHIC RETICLE

MANUFACTURING WITH IMPROVED ETCH BIAS

Transmitted herewith is the patent application identified above, including:

X Specification, claims and abstract, totaling 24 pages.

X Drawings totaling 3 pages, X Formal \_\_\_ Informal.

Executed Declaration and Power of Attorney.

\_\_\_ Information Disclosure Statement w/ Form 1449 and References.

\_\_\_ Assignment of the invention to Applied Materials, Inc.

\_\_\_ Assignment Recordation Cover Sheet

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	0.010 1 00	aims Fee	Rate Total
Total Claims 24	-20=	4 x \$18	3.00 \$72.00
Independent 3	-3=	0 x \$84	\$84.00
Basic Filing Fee		\$740	.00 \$740.00

- The Commissioner is hereby authorized to charge \$896.00 to Deposit Account No. 50-1074/AMAT/5813/ETCH/METAL/JB.
- The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. <u>50-1074/5813/ETCH/METAL/JB</u>. A duplicate copy of this transmittal is enclosed.
- X Please address all future correspondence to:

PATENT COUNSEL

APPLIED MATERIALS, INC.

**Legal Affairs Department** 

**P.O.BOX 450A** 

Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner for Patents, Box Patent Application, Washington, DC 20231.

Express Mail Receipt No.:

EV 041916383 US

Date of Deposit

Robert W. Mulcahy

Respectfully submitted

Registration No. 25,436

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JC720 U.S. PTO 10/024958